

# INTERNATIONAL SEARCH REPORT

International Application No  
P/US2004/041884

<b>A. CLASSIFICATION OF SUBJECT MATTER</b> IPC 7 G01N21/956 G01B11/24 H01L21/66 G03F7/20 G06T7/00 G01N23/22				
According to International Patent Classification (IPC) or to both national classification and IPC				
<b>B. FIELDS SEARCHED</b> Minimum documentation searched (classification system followed by classification symbols) IPC 7 G01N G01B H01L G03F G06T				
Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched				
Electronic data base consulted during the international search (name of data base and, where practical, search terms used) EPO-Internal, INSPEC, COMPENDEX				
<b>C. DOCUMENTS CONSIDERED TO BE RELEVANT</b>				
Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.		
X	US 6 480 807 B1 (MIYANO YUMIKO) 12 November 2002 (2002-11-12)  column 2, line 61 - column 3, line 3 column 3, lines 20-28 column 6, lines 7-23 column 8, lines 5-45 ----- -/--	1-15, 17-31, 33-38		
<input checked="" type="checkbox"/> Further documents are listed in the continuation of box C.				
<input checked="" type="checkbox"/> Patent family members are listed in annex.				
<b>* Special categories of cited documents :</b> <table border="0"> <tr> <td>           *A* document defining the general state of the art which is not considered to be of particular relevance            *E* earlier document but published on or after the international filing date            *L* document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified)            *O* document referring to an oral disclosure, use, exhibition or other means            *P* document published prior to the international filing date but later than the priority date claimed         </td> <td>           *T* later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention            *X* document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone            *Y* document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art.            *&amp;* document member of the same patent family         </td> </tr> </table>			*A* document defining the general state of the art which is not considered to be of particular relevance *E* earlier document but published on or after the international filing date *L* document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified) *O* document referring to an oral disclosure, use, exhibition or other means *P* document published prior to the international filing date but later than the priority date claimed	*T* later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention *X* document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone *Y* document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art. *&* document member of the same patent family
*A* document defining the general state of the art which is not considered to be of particular relevance *E* earlier document but published on or after the international filing date *L* document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified) *O* document referring to an oral disclosure, use, exhibition or other means *P* document published prior to the international filing date but later than the priority date claimed	*T* later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention *X* document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone *Y* document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art. *&* document member of the same patent family			
Date of the actual completion of the international search  15 April 2005		Date of mailing of the international search report  27/04/2005		
Name and mailing address of the ISA European Patent Office, P.B. 5818 Patentlaan 2 NL - 2280 HV Rijswijk Tel. (+31-70) 340-2040, Tx. 31 651 epo nl, Fax: (+31-70) 340-3016		Authorized officer  Navas Montero, E		

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X,P	LEE TAE YONG ET AL.: "Experimental methodology of contact edge roughness on sub-100 nm pattern" PROCEEDINGS OF SPIE: METROLOGY, INSPECTION, AND PROCESS CONTROL FOR MICROLITHOGRAPHY XVIII, vol. 5375, 24 May 2004 (2004-05-24), pages 623-632, XP002324803 USA the whole document	1-5, 7-15, 17-21, 23-31, 33-38
X	BUNDAY BENJAMIN D. ET AL.: "CD-SEM Measurement of Line Edge Roughness Test Patterns for 193 nm Lithography" PROCEEDINGS OF SPIE: PROCESS AND MATERIALS CHARACTERIZATION AND DIAGNOSTICS IN IC MANUFACTURING, vol. 5041, July 2003 (2003-07), pages 127-141, XP002324804 USA page 129, lines 1-31 page 133, lines 5-8	16, 32
A	EP 1 279 923 A (HITACHI, LTD) 29 January 2003 (2003-01-29) the whole document	1, 16, 17, 33-38

# INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No

JP/US2004/041884

Patent document cited in search report		Publication date		Patent family member(s)	Publication date
US 6480807	B1	12-11-2002	JP	2001091231 A	06-04-2001
EP 1279923	A	29-01-2003	JP	2003037139 A	07-02-2003
			EP	1279923 A2	29-01-2003
			US	2003021463 A1	30-01-2003